Chemical Vapor Deposition Cvd Equipment System Chamber Slide Pecvd Tube Furnace With Liquid Gasifier Pecvd Machine

Item Number: KT-PE12

Introduction

KT-PE12 Slide PECVD System: Wide power range, programmable temp control, fast heating/cooling with sliding system, MFC mass flow control & vacuum pump.

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Furnace model	KT-PE12-60
Max. temperature	1200℃
Constant work temperature	1100℃
Furnace tube material	High purity quartz
Furnace tube diameter	60mm
Heating zone length	1x450mm
Chamber material	Japan alumina fiber
Heating element	Cr2Al2Mo2 wire coil
Heating rate	0-20℃/min
Thermal couple	Build in K type
Temperature controller	Digital PID controller/Touch screen PID controller
Temperature control accuracy	±1℃
Sliding distance	600mm
RF Plasma unit	
Output Power	5 -500W adjustable with ± 1% stability
RF frequency	13.56 MHz ±0.005% stability
Reflection Power	350W max.
Matching	Automatic
Noise	<50 dB
Cooling	Air cooling.
Gas precise control unit	
Flow meter	MFC mass flow meter
Gas channels	4 channels
Flow rate	MFC1: 0-5SCCM O2 MFC2: 0-20SCMCH4 MFC3: 0- 100SCCM H2 MFC4: 0-500 SCCM N2

Linearity	±0.5% F.S.
Repeatability	±0.2% F.S.
Pipe line and valve	Stainless steel
Maximum Operating Pressure	0.45MPa
Flow meter controller	Digital Knob controller/Touch screen controller
Standard vacuum unit(Optional)	
Vacuum pump	Rotary vane vacuum pump
Pump flow rate	4L/S
Vacuum suction port	KF25
Vacuum gauge	Pirani/Resistance silicon vacuum gauge
Rated vacuum pressure	10Pa
High vacuum unit(Optional)	
Vacuum pump	Rotary vane pump+Molecular pump
Pump flow rate	4L/S+110L/S
Vacuum suction port	KF25
Vacuum gauge	Compound vacuum gauge
Rated vacuum pressure	6x10-4Pa
Above specifications and setups can be customized	

No.	Description	Quantity
1	Furnace	1
2	Quartz tube	1
3	Vacuum flange	2
4	Tube thermal block	2
5	Tube thermal block hook	1
6	Heat resistant glove	1
7	RF plasma source	1
8	Precise gas control	1
9	Vacuum unit	1
10	Operation manual	1